

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Applicants: Den Toonder, *et al.* Docket No.: EPC-018  
Serial No.: 10/578,027 Art Unit: 1733  
Filed: November 6, 2008 Examiner: Janell C. Morillo  
For: Radio-Frequency Microelectromechanical Systems and a Method of  
Manufacturing Such Systems

Commissioner for Patents  
P. O. Box 1450  
Alexandria, VA 22313-1450

**INFORMATION DISCLOSURE STATEMENT**

Dear Sir:

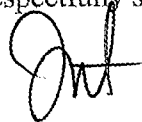
The Applicants wish to bring to the attention of the Patent and Trademark Office the information noted on the enclosed form PTO/SB/08a that may be considered material to the examination of the above-identified application. A copy of the U.S. Patent cited is not being submitted. However, Applicants have included a copy of the cited foreign patent.

No fee is due at this time, as this Information Disclosure Statement is being filed pursuant to 37 C.F.R. § 1.97(c)(1). Applicants hereby state that each item of information contained in this statement was first cited in a communication from a foreign patent office in a counterpart application not more than three months prior to the filing of this statement. As a result, no fee is due at this time. A copy of the Japanese Examination Report is provided for the Examiner's convenience.

11/20/2011

Date

Respectfully submitted,



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